

Advanced Surface Nitriding

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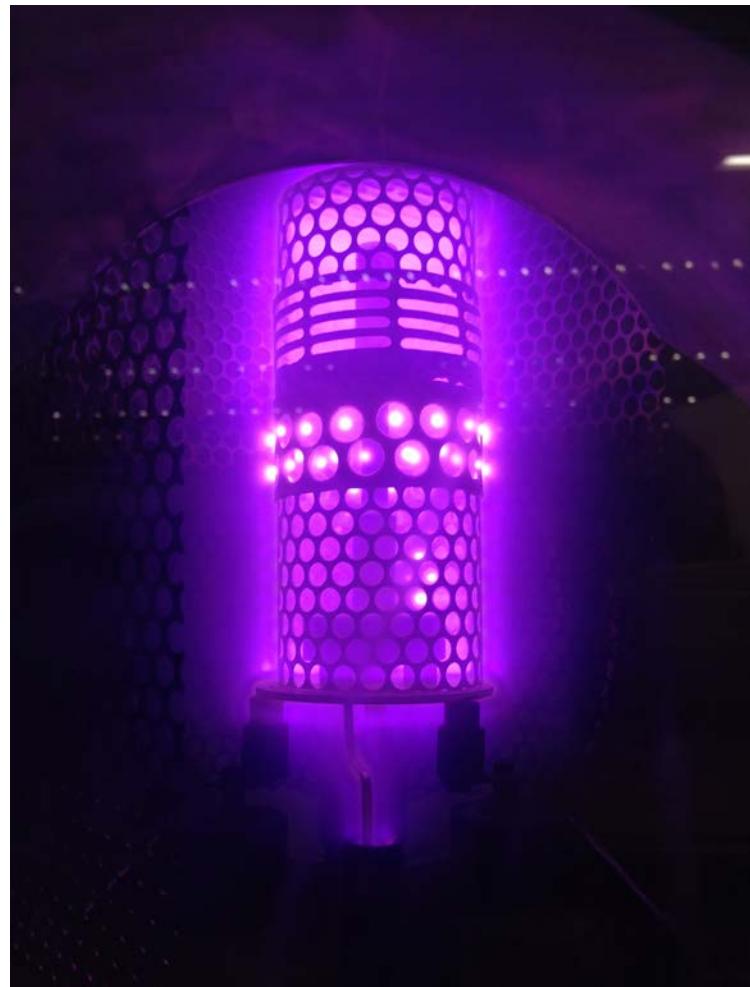
Texas A&M Nuclear Engineering

Why Nitride

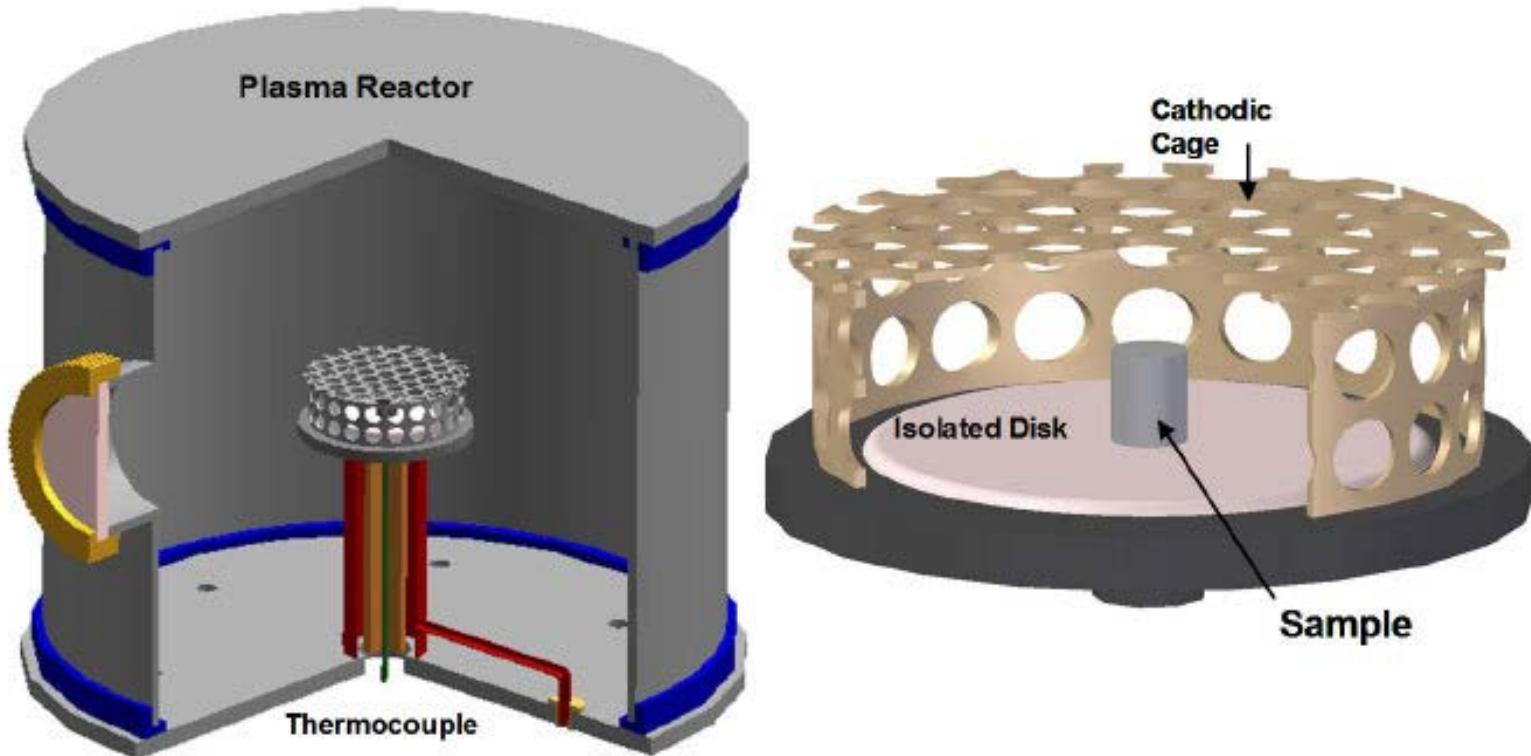
- Low-temperature process
- No quench requirement
- Minimal distortion
- Resistance to oxidation
- High hardness values
- Same core properties

Basic Theory

- Large voltage frees bound electrons
- Particle acceleration
- Vacuum increase mfp => greater energy
- Ions collide to give off visible light



Initial Design



Initial nitriding chamber design [1].

Problems with Initial Design

- Severe arcing when igniting plasma
- Metallic sputter deposition on all ceramic insulators resulting in electrical shorting
- Sample insulation disc shorting due to sputter deposition
 - Inconsistent nitriding results
- High maintenance due to cleaning ceramic every experiment

Solutions

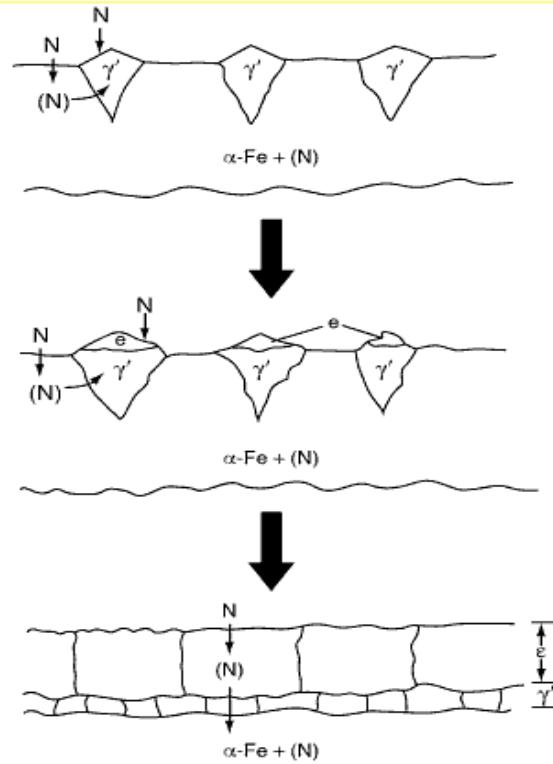
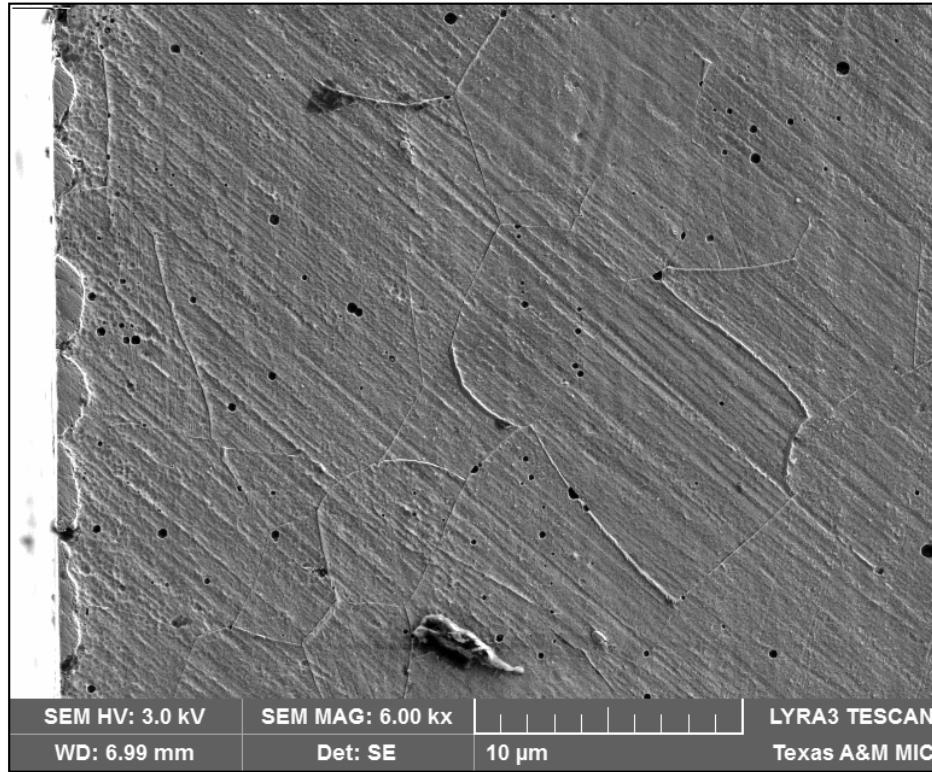
- Adjustable anode (electrical ground)
- Replaced isolation disc with multiple shielded sample holders
- Added shields to thermocouple feedthrough and stage ceramic stands

Current Experiment Matrix

- Metals Nitrided
 - 316L
 - HT9
 - T91
 - Zircaloy 4
 - Pure Iron
- Gas: N₂/H₂ (90%/10%)
- Cage: SS316

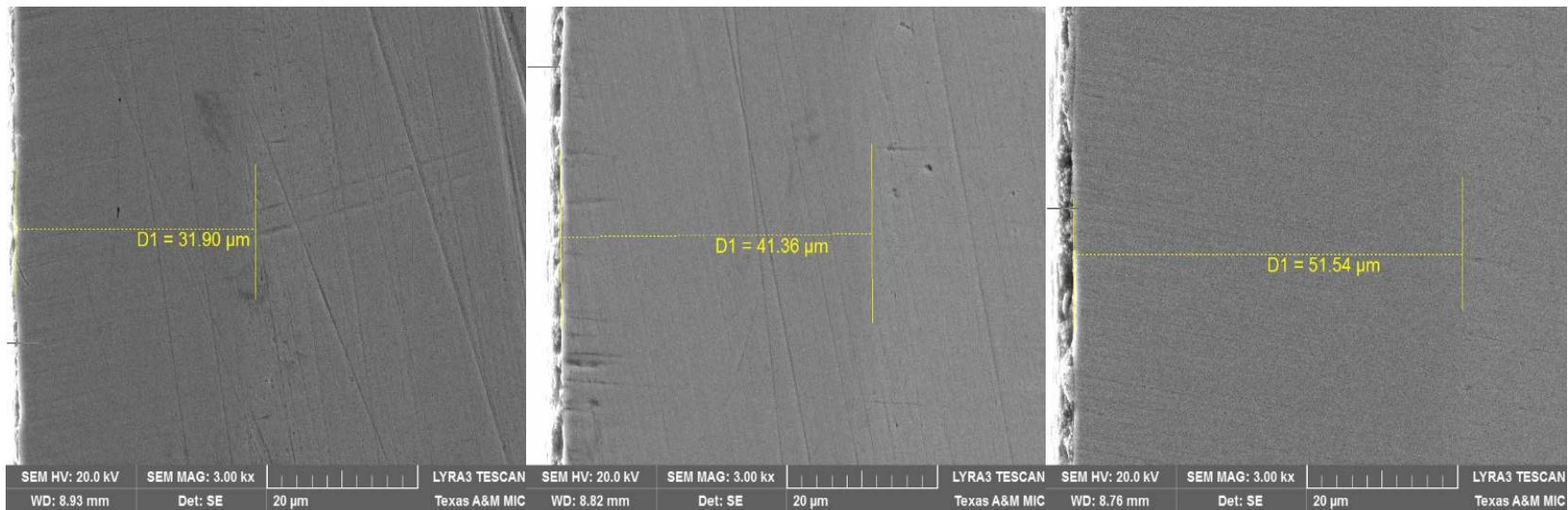
Pressure (mTorr)	Temperature (°C)		
	400	450	525
750	1 Hr	30 min	30 min
	2 Hr	1 Hr	1 Hr
	4 Hr	2 Hr	2 Hr
1000	1 Hr	30 min	30 min
	2 Hr	1 Hr	1 Hr
	4 Hr	2 Hr	2 Hr
1500	1 Hr	30 min	30 min
	2 Hr	1 Hr	1 Hr
	4 Hr	2 Hr	2 Hr

316L Nitride Layer at 375C for 2 Hours



Initial formation of nitride layer [2].

316L:525C, 1Torr Cross Section Polishing Before Etching

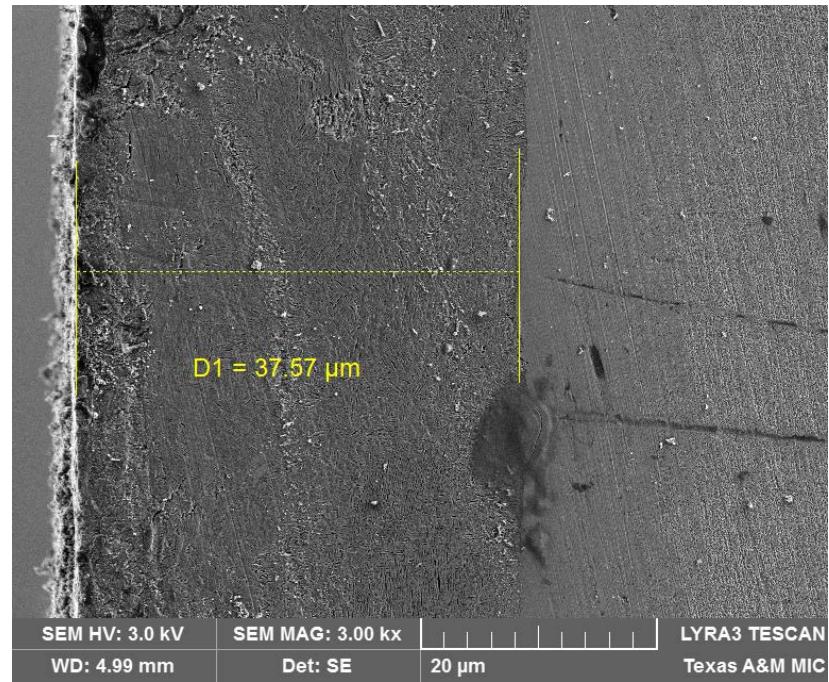
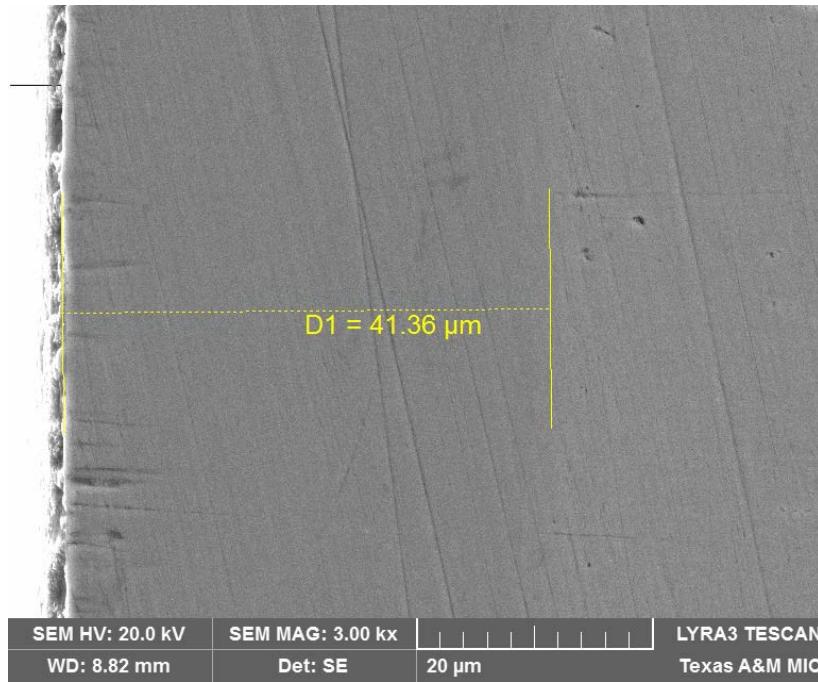


30 mins

1 Hour

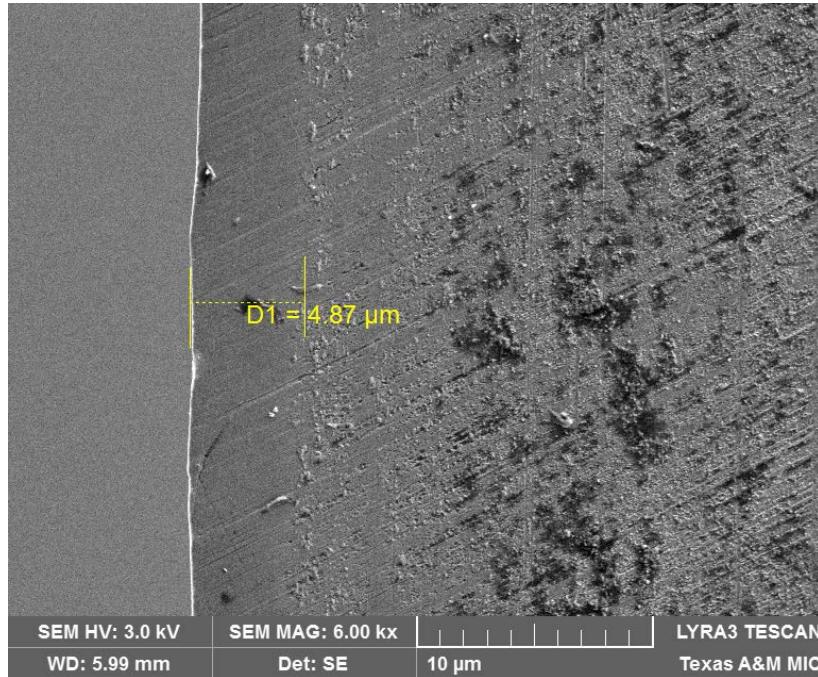
2 Hours

316L: 525C, 1Torr, 1Hr

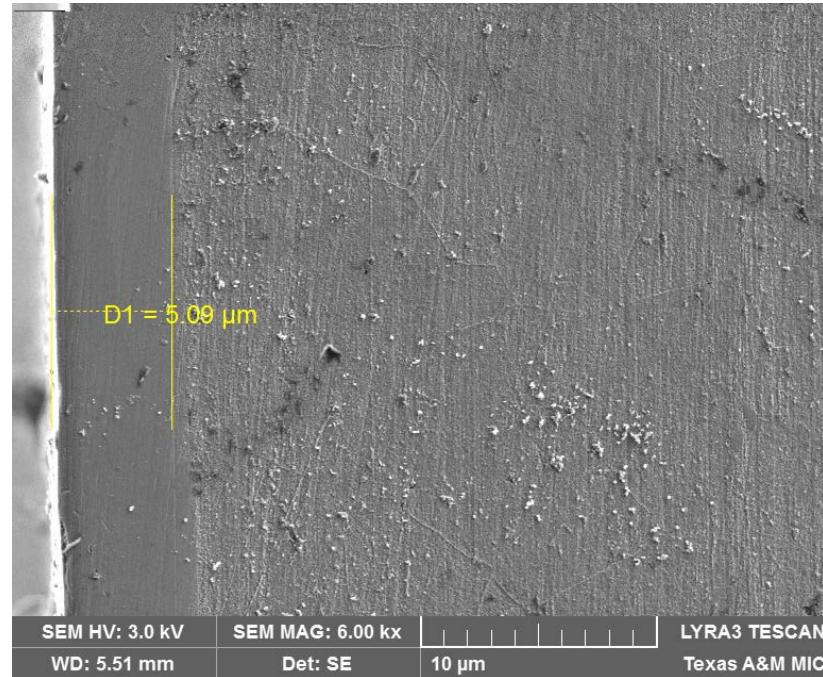


Before and after etching with Marble's reagent.

316L: 400C, 2 Hours

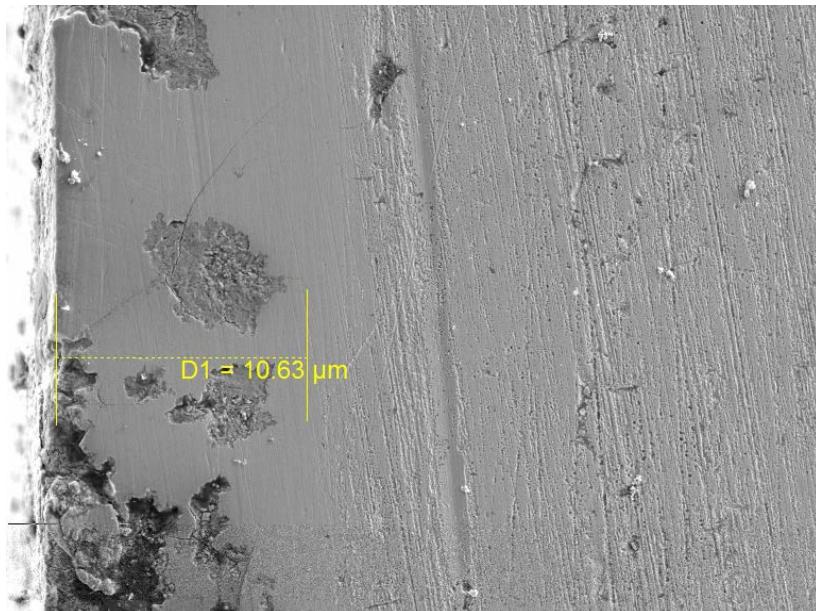


1 Torr

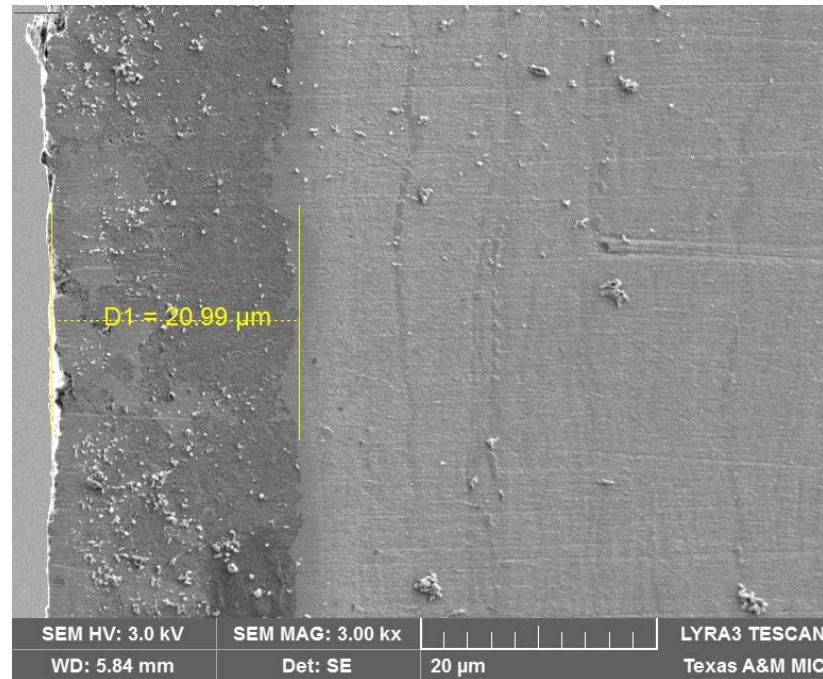


1.5 Torr

316L: 450C

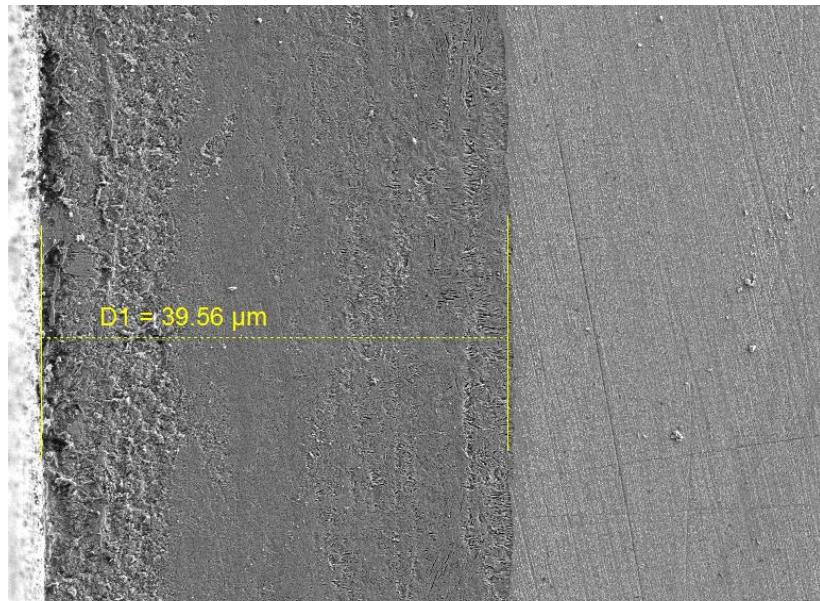


1 Hour
750 mTorr



2 Hours
1 Torr

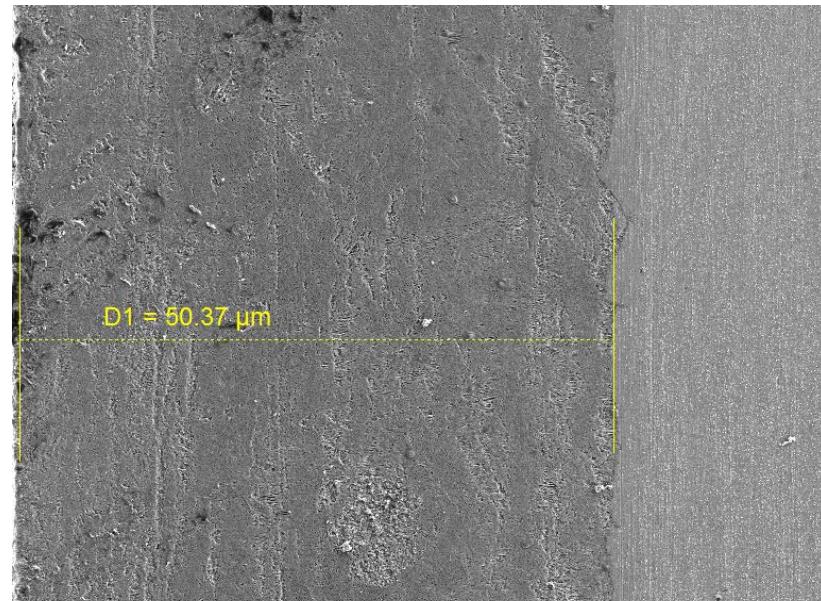
316L: 525C, 1.5 Torr



SEM HV: 3.0 kV	SEM MAG: 3.00 kx	[scale bar]
WD: 6.14 mm	Det: SE	20 μm

LYRA3 TESCAN
Texas A&M MIC

1 Hour



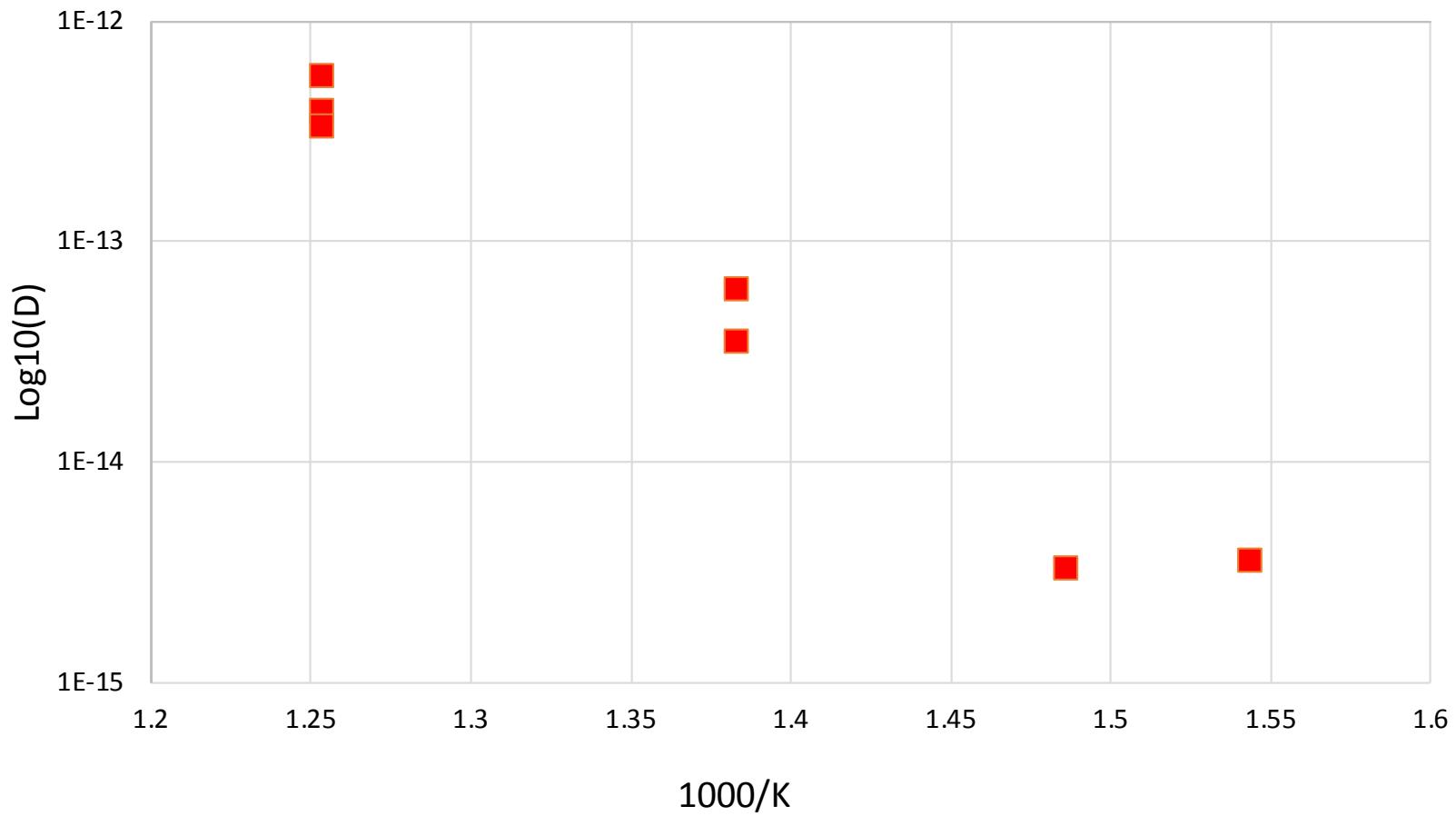
SEM HV: 3.0 kV	SEM MAG: 3.00 kx	[scale bar]
WD: 5.60 mm	Det: SE	20 μm

LYRA3 TESCAN
Texas A&M MIC

2 Hour

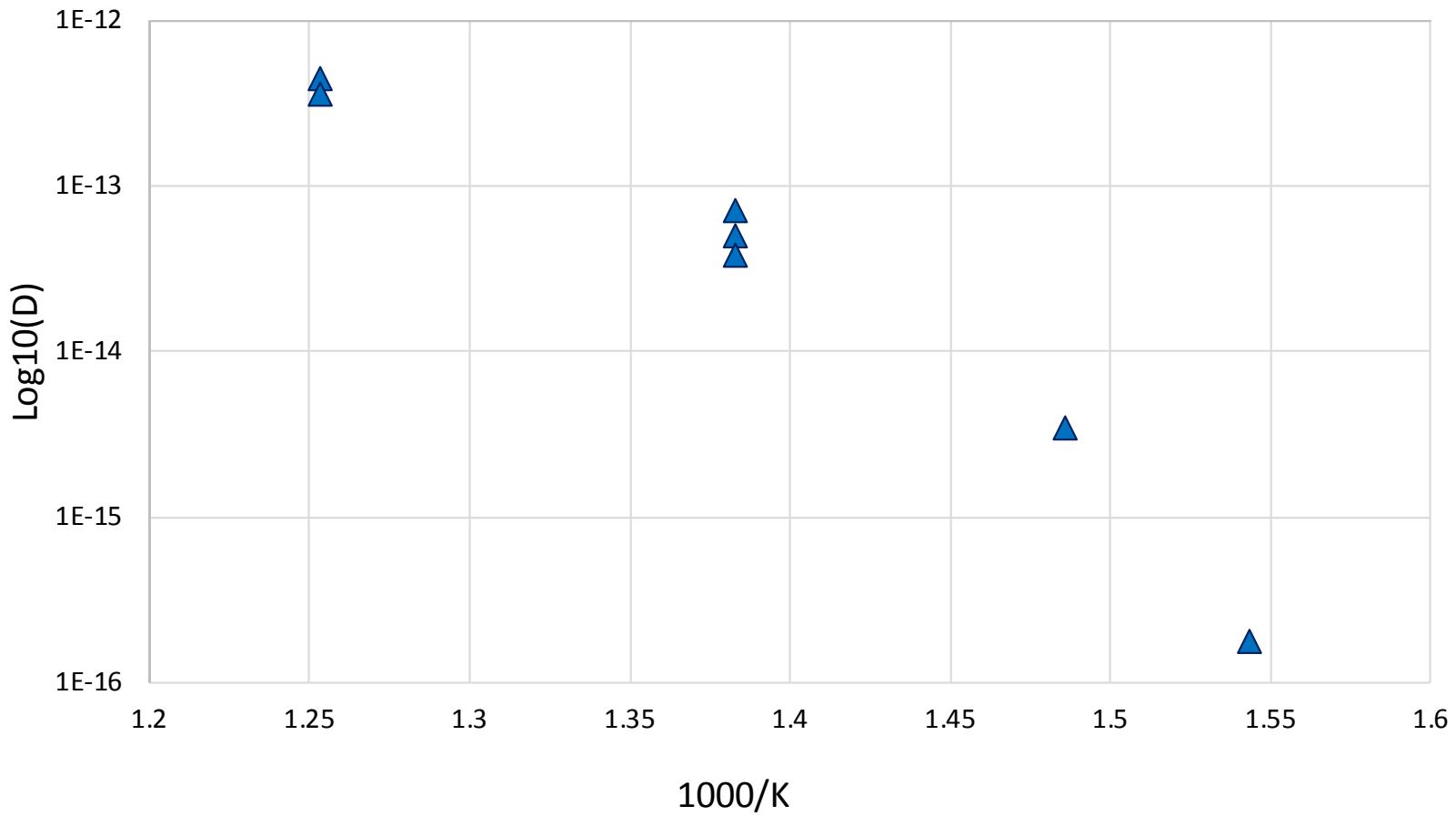
Diffusion Kinetics: 316L

1.0 Torr

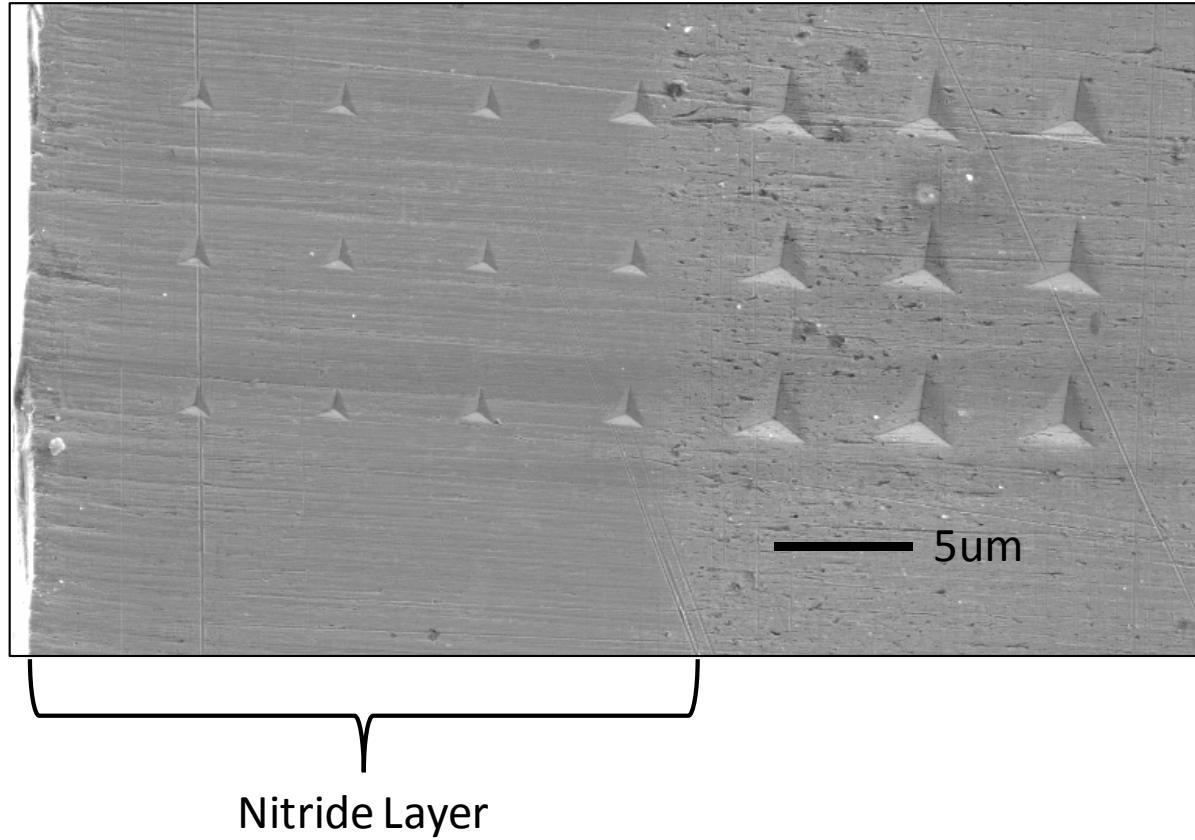


Diffusion Kinetics: 316L

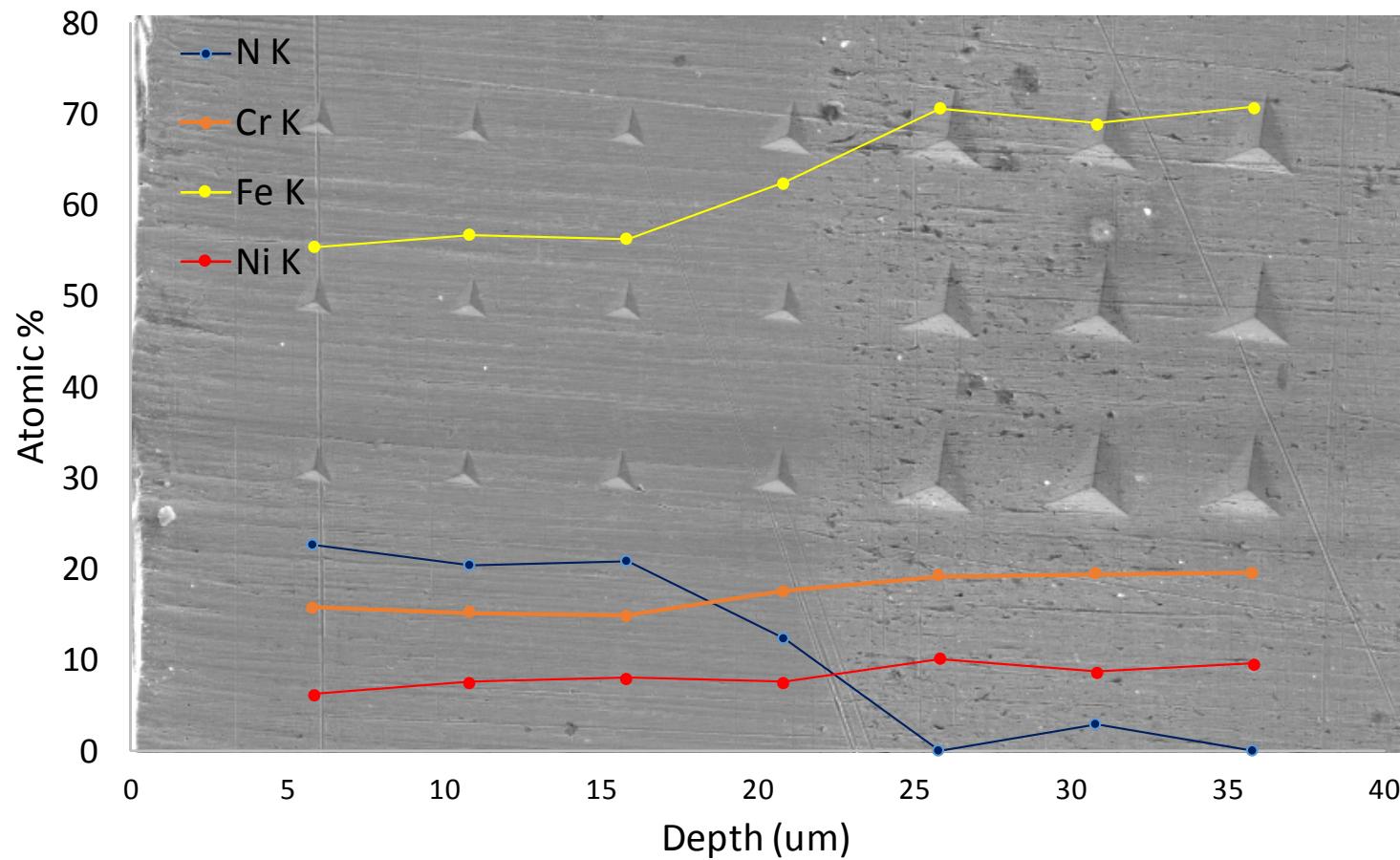
1.5 Torr



316L: 450C, 1.5Torr, 2Hr

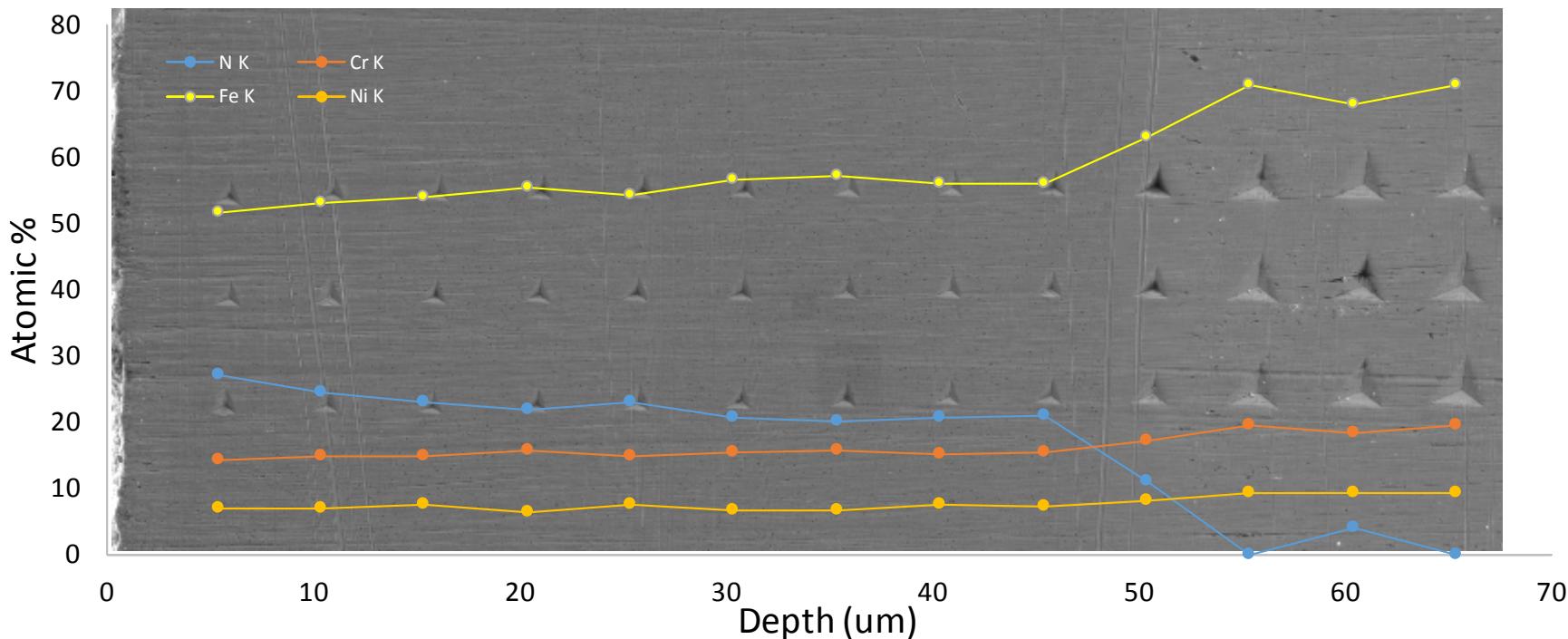


316L: 450C, 1.5Torr, 2Hr



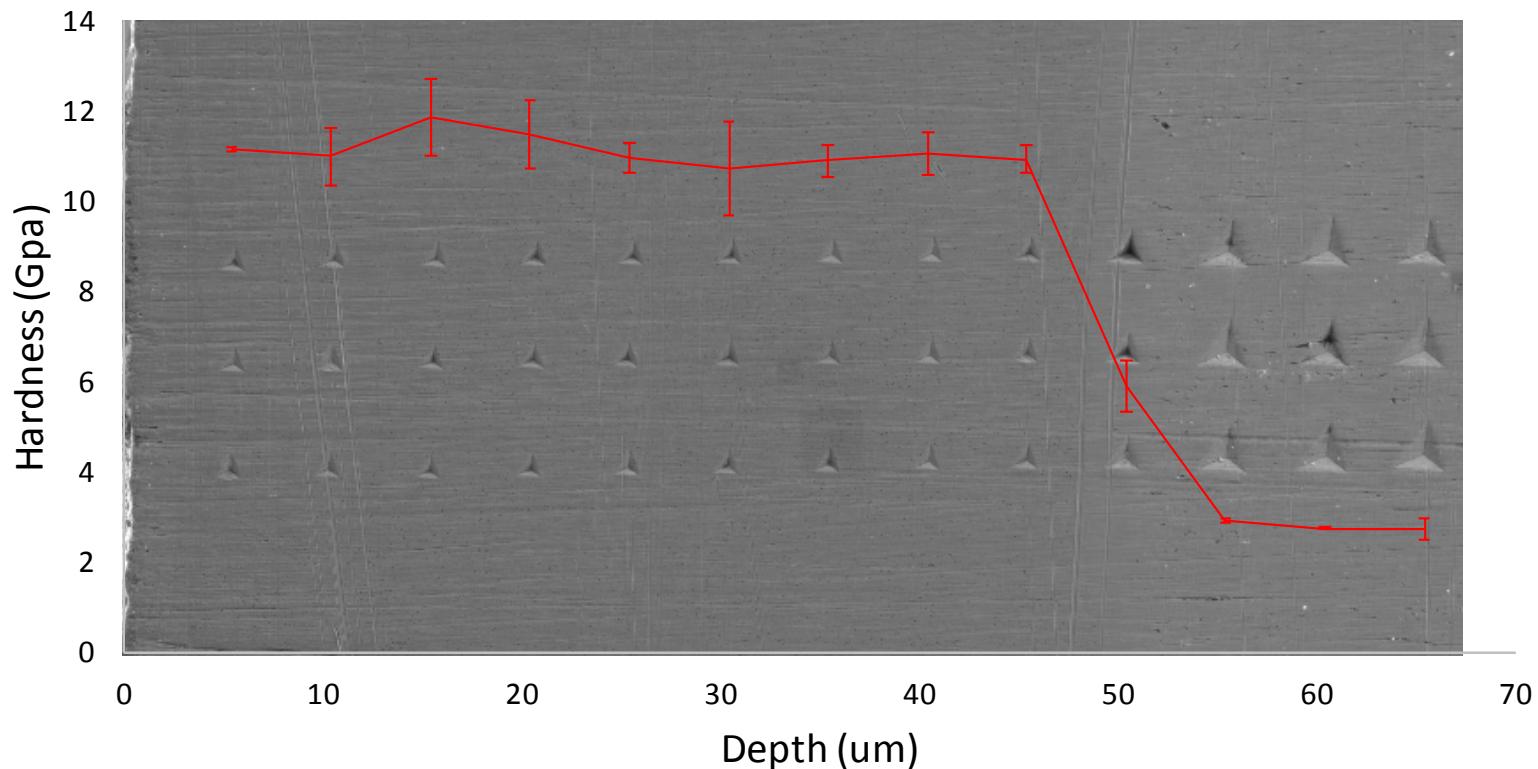
316L: 525C, 1Torr, 2Hr

Atomic Percentage Vs. Depth



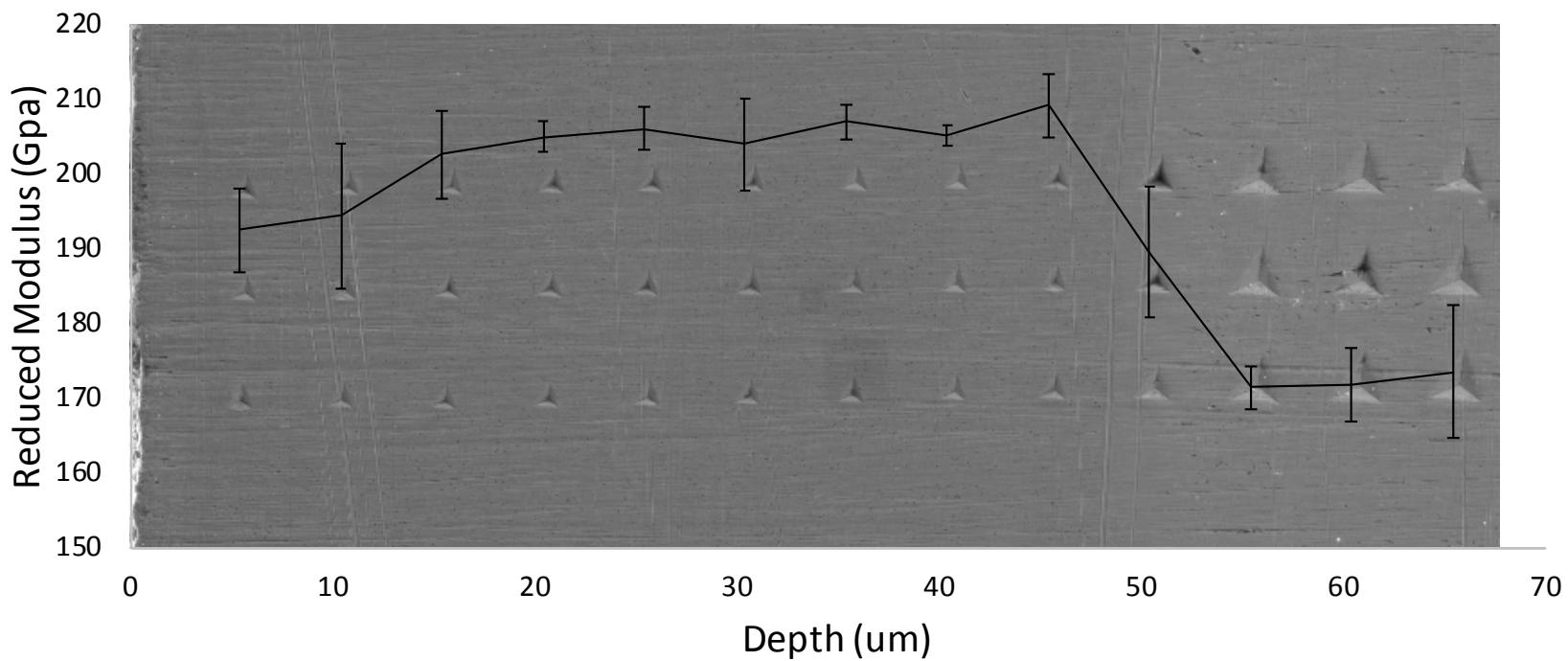
316L: 525C, 1Torr, 2Hr

Hardness Vs. Depth

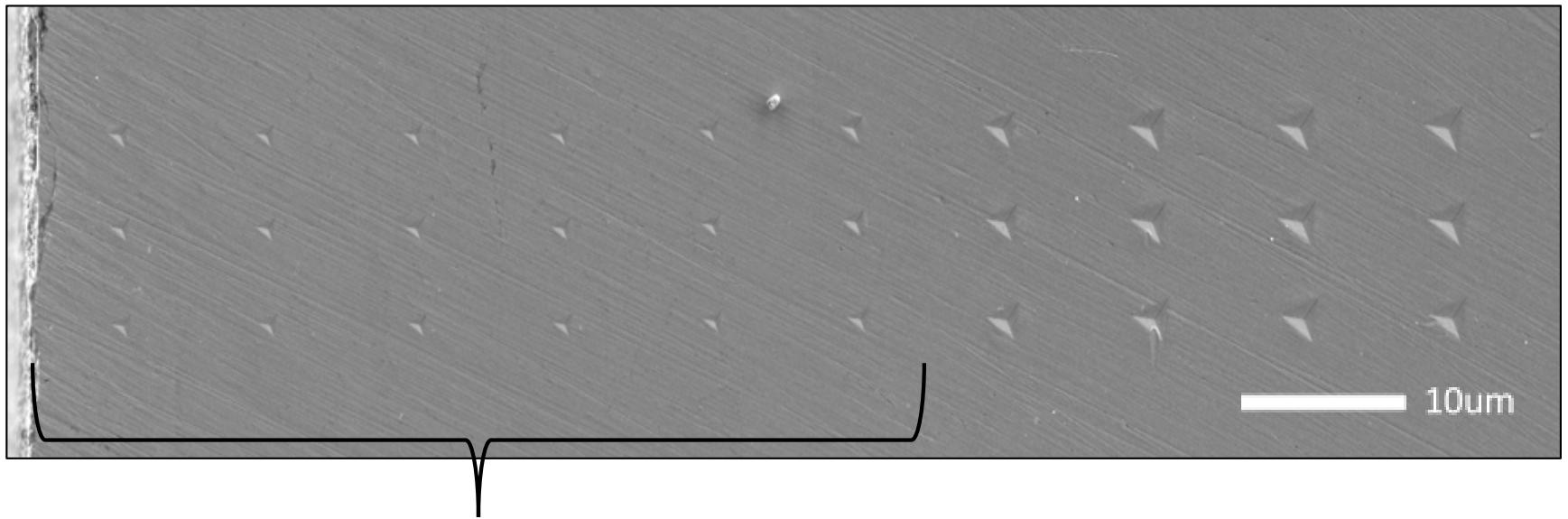


316L: 525C, 1Torr, 2Hr

Reduced Modulus Vs. Depth



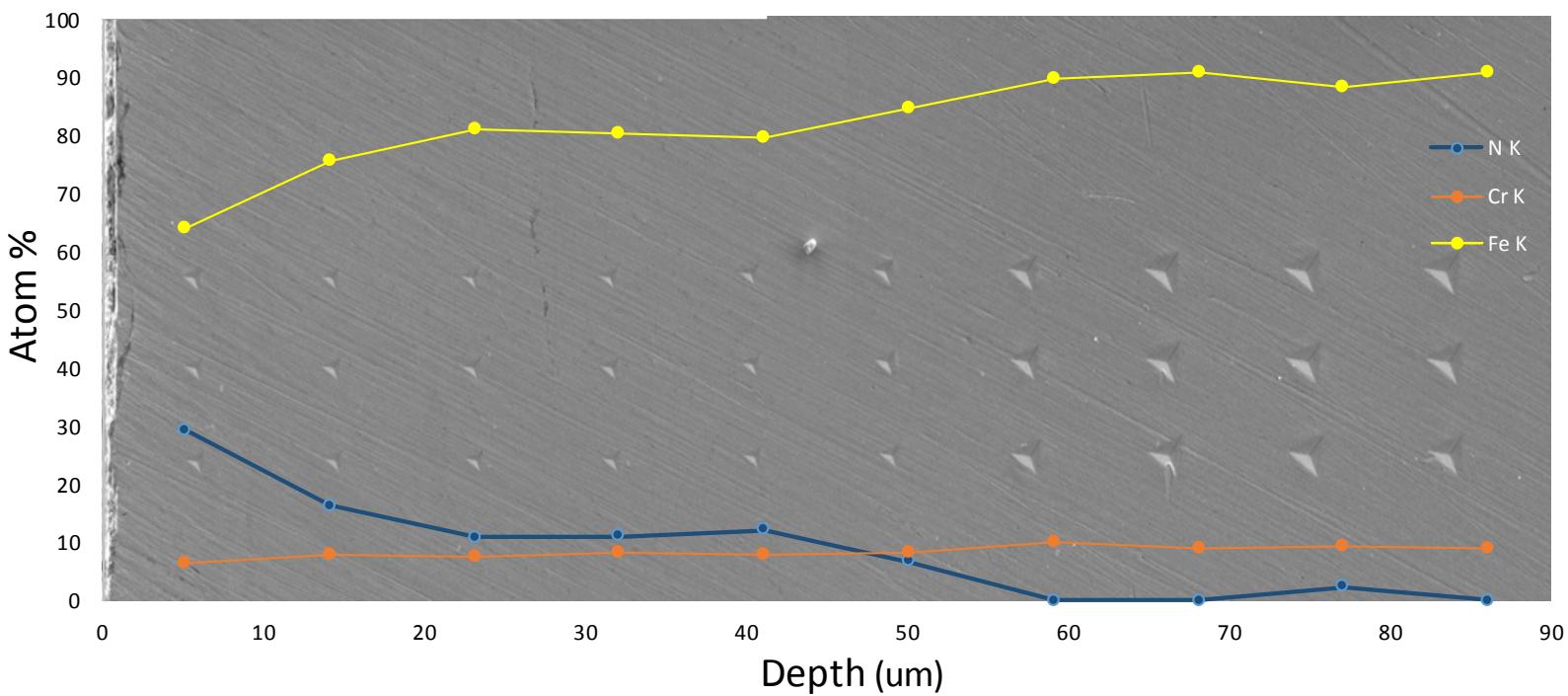
T91: 450C, 1.5Torr, 2Hr



Nitride Layer

T91: 450C, 1.5Torr, 2Hr

Atom Percent Vs. Depth



Cathodic Cage Nitriding



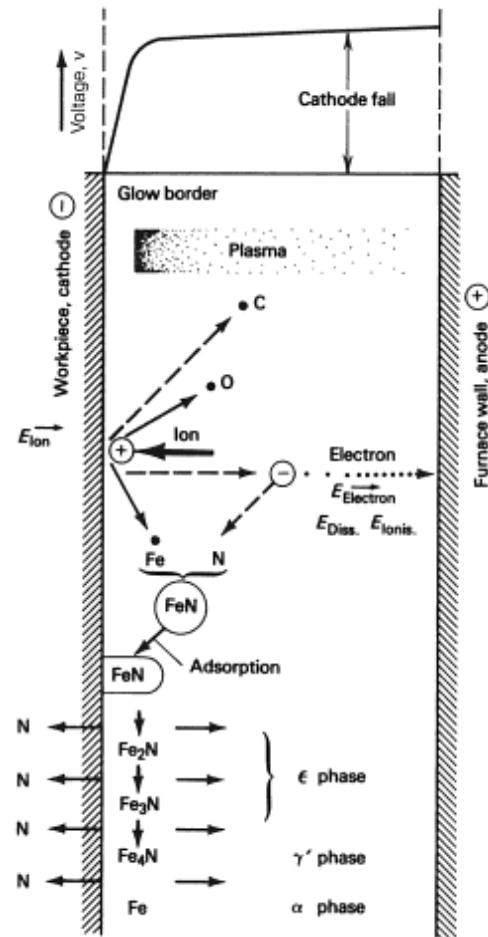
Future Work

- Analyze nitrided HT9, Zircaloy4, T91, Pure Iron, Pure Zirconium
- Measure how cage thickness changes Hollow Cathode Effect

Questions?

- 1) R.R.M. de Sousa, et al., *Cathodic cage plasma nitriding of austenitic stainless steel (AISI 316): influence of the working pressure on the nitrided layers properties*, Mater. Res., 17 (2014), pp. 427–433
- 2) Pye, D., *Practical Nitriding and Ferritic Nitrocarburizing*. 2003, Materials Park, OH: ASM International. 256.

Glow discharge ion nitriding mechanisms



Hollow Cathode Effect

